

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

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Rovira; and Roger R. Lowe-Webb

Nanometrics Incorporated

Title:

Apparatus and Method for the Measurement of Diffracting Structures

Serial No.:

09/670,000

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Chih-Cheng Glen Kao

Group Art Unit:

2882

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3656

Santa Clara, California April 7, 2006

Mail Stop RCE Commissioner For Patents P.O. Box 1450 Alexandria, VA 22313-1450

RESPONSE TO OFFICE ACTION

Dear Sir:

This Response to Office Action is responsive to the October 14, 2005, Office Action, which has a statutorily shortened period for response that ends January 14, 2006. A petition for a 3 month extension is filed herewith, giving applicants until April 14, 2006, to respond. Please enter the following amendments before taking action on the merits of the above-referenced application. This amendment is being filed with a Request for Continued Examination (RCE).

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